This listing of claims will replace all prior versions, and listings, of claims in the application:

The Status of the Claims

(Original): A method of making a MOS transistor, the method comprising:
providing a semiconductor substrate comprising a polysilicon gate electrode
with a silicide layer thereon, a spacer which is formed on both lateral walls of said
polysilicon gate electrode, and source and drain regions with lightly doped drain regions
which are formed at both sides of said polysilicon gate electrode;

forming an insulating layer on the area of said substrate including said polysilicon gate electrode;

polishing said insulating layer so that the top of said polysilicon gate electrode is exposed;

etching some part of said insulating layer and said spacer so that both lateral walls of said polysilicon gate electrode are exposed;

forming a metal layer on said substrate resulted from the preceding step so that said polysilicon gate electrode is covered with said metal layer; and

transforming completely said polysilicon gate electrode into a metal silicide gate electrode by performing a thermal treatment process for said substrate coated with said metal layer.

- 2. (Original): A method as defined by claim 1, wherein said spacer and said insulating layer comprise the same material.
- 3. (Original): A method as defined by claim 1, wherein said insulating layer and said spacer are etched until said polysilicon gate electrode is exposed to between about 4/6 and about 5/6 of its height.

Application No. 10/627,059 Attorney Docket: 20063/G03-010

- 4. (Original): A method as defined by claim 1, wherein said metal layer comprises a multilayer including transition metals and their alloys.
- 5. (Original): A method as defined by claim 1, wherein said thermal treatment process comprises one or more steps of a rapid thermal process.
- 6. (Original): A method as defined by claim 1, wherein said thermal treatment process is performed at the temperature between about 400°C and about 600°C in a first step and between about 800°C and about 1000°C in a second step.

Claims 7-13: cancelled without prejudice.